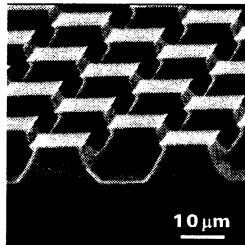
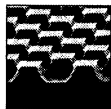


ULTRASHARP
CANTILEVERS & GRATINGS

TGX01

[test structure]

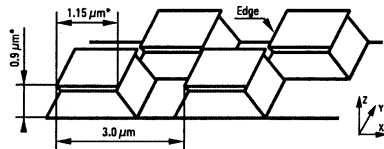


SEM image of the silicon grating TGX01.

Grating Characteristics:

Active area	2x2 mm
Radius of curvature of a pillar edge	less than 5 nm
Pitch	3 μm
Accuracy of pitch	±5 nm

TGX01



The dimensions marked * are given for information only .

Silicon calibration gratings of the **TGX01** series comprise a chessboard-like array of square pillars with sharp undercut edges formed by $\langle 110 \rangle$ silicon crystallographic directions. The pitch is $3 \mu\text{m}$. The radius of curvature of a pillar edge is less than 5 nm. These gratings are used as test structures for the lateral calibration of SPM scanners, assessment of lateral nonlinearity, detection of hysteresis, and piezoceramics creep-effect.